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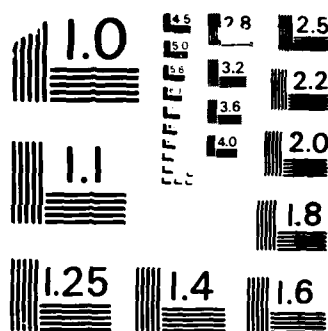
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MEASURING AND MODELLING THE
TRANSITION LAYER DURING THE DISSOLUTION
OF GLASSY POLYMER FILMS

by

P. D. Krasicky, R. J. Groele, and F. Rodriguez

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20. ABSTRACT (Continue on reverse side if necessary and identify by block number) The technique of laser interferometry is now routinely used by the micro-electronics industry for the measurement of the dissolution rates of thin polymer films. In addition to the rate of dissolution, laser interferometry can also provide quantitative information on the thickness of the transition layer between the dissolving glassy polymer and the liquid solvent. This paper describes how observed patterns of reflected light intensity may be analyzed to calculate the thickness of the transition layer for polymers that dissolve		

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with little or no swelling. The technique required knowledge of the shape of the concentration profile in the transition layer. However, by assuming various simple model profiles one may obtain a reasonable estimate. Experimental measurements of PMMA films dissolving in methyl ethyl ketone indicate transition layers of thicknesses 0 to 0.1 μm for PMMA of molecular weights $M_w = 37,000$ to 1,400,000.

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TRANSITION LAYER DURING THE DISSOLUTION
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INTRODUCTION

Over the past few years there has been a renewed interest in the study of polymer swelling and dissolution behavior. Most theoretical models have concentrated on diffusion and swelling,¹⁻⁴ but some work is also being done on dissolution.⁵⁻⁷ The wide variety of observed phenomena is indicative of the complexity of the problem. Experimentally, many techniques and sample geometries have been used.⁸ Optical microscopy⁹⁻¹² has proven useful for the study of swelling and dissolution behavior since it allows measurement of the rate of dissolution and observation of the concentration profile in the dissolving surface layer. However, microscopy works best when the dimensions being observed are 10 μm or greater. Rutherford Backscattering Spectroscopy¹³ may be used to make measurements on much smaller dimensions, but since it cannot be done in situ and requires special sample preparation procedures, it is limited to the study of swelling only.

This paper was presented in part at the National Meeting of the Amer. Inst. of Chem. Engs., Boston, August 24-27, 1986.

Of particular interest to the microelectronics industry is the dissolution of a 1 μm thick polymer film on a silicon substrate. The technique of laser interferometry^{9,11} is now routinely used for the screening of new polymer-solvent systems and for the optimization of processing conditions. Not so obvious in the use of laser interferometry is the quantitative information it can provide on the dissolving surface layer for polymers that dissolve with little or no swelling.

DISSOLUTION RATE MEASUREMENT USING LASER INTERFEROMETRY

Laser interferometry is popular as the method of dissolution rate measurement since the sample geometries and substrate materials of typical microlithographic processes can be used. The basic apparatus for laser interferometry is shown in figure 1. A silicon wafer that has been coated with a 0.5 to 1.5 μm thick film of polymer is suspended in a transparent cylindrical container filled with the developing solvent. The solvent container includes a magnetic stirrer and a heating/cooling coil connected to a temperature bath. The beam from an unpolarized He-Ne laser of wavelength 6328 Å is directed obliquely at the coated substrate with an incident angle of typically 10°. The reflected beam is collected by a silicon photocell and the recorded signal represents the reflected intensity as a function of time. A more complete description of the technique is given by Krasicky et. al.¹¹

As the polymer film dissolves, the reflected intensity should oscillate due to thin film interference effects. The quantity of interest is the reflectance R which is defined as the ratio of the reflected light intensity to the incident light intensity. A sufficiently accurate expression for the reflectance R is

$$R = r_{ps}^2 + 2r_{ps}r_{sp}(1 - r_{ps}^2)\cos\theta_p \quad (1)$$

Here r_{ps} and r_{sp} are the Fresnel reflection coefficients for the polymer/substrate and solvent/polymer interfaces, respectively. The phase angle θ_p is the difference in phase between light rays reflected from the two interfaces. The phase angle is given by

$$\theta_p = \frac{4\pi d \sqrt{n_s^2 - n_p^2 \sin^2\theta_i}}{\lambda} \quad (2)$$

Where d is the thickness of the polymer film, λ is the free space wavelength of the light, θ_i is the incident angle of the light, and n_s and n_p are the refractive indices of the solvent and polymer. Figure 2 is a sketch of a typical observed reflected intensity pattern. As expected the reflected intensity oscillates sinusoidally until the film is completely dissolved, after which the reflectance from the bare substrate is constant. From a reflectance-time trace such as figure 2, measurement of

the reflectance ratio a/b and the period of oscillation T allows calculation of the dissolution rate of the polymer film and the polymer's refractive index. Values of the refractive indices of the substrate and solvent, the wavelength of light, and the incident angle must also be known.

The above analysis applies only if the solvent/polymer interface is perfectly sharp. For some polymer-solvent systems this interface is not perfectly sharp, but is expanded into a continuous transition layer of nonzero thickness. The appropriate expression for the reflectance is now

$$R = n_0^2 n_s^2 + 2f n_0 n_s (1 - n_0^2) \cos \theta \quad (3)$$

Here f is a positive factor less than unity multiplying the reflection coefficient n_0^2 and $\theta = \theta_0 + \theta_1$. Both f and the phase angle θ_1 depend on the thickness and shape of the concentration profile in the transition layer. The effect of the transition layer is to reduce the amplitude of the reflectance oscillations by the factor f while preserving the average value of the reflectance, and to shift the oscillations' phase by θ_1 . The amplitude reduction factor f is measured as a gap or offset created between the maximum value of reflectance in the oscillations and the reflectance of the bare substrate after the film has completely dissolved (see figure 3).

$$f = \frac{a - b}{(a + s) - (b - s)} \quad (4)$$

The phase angle ϕ , is measured in terms of the time interval t_ϕ between the observed endpoint of dissolution and the next expected maximum relative to the period for a complete oscillation.

$$\phi = \left(\frac{t_\phi}{T} \right) 360^\circ \quad (5)$$

Correction for Silicon Oxide Layer

A small correction needs to be made when a silicon wafer is used as the substrate material. A very thin layer of silicon oxide is always present and can account for an additional phase shift given approximately by

$$\phi_o = \frac{4\pi d_o n_o}{\lambda} \quad (6)$$

where d_o is the thickness of the silicon oxide layer, n_o is its refractive index, and λ is the wavelength of light used. For the silicon substrates used in this work the thickness of the native oxide layer was measured by ellipsometry to be about 21 Å. This can account for a phase shift of 3.5° which must be subtracted from the measured value of ϕ , to get the phase shift due to the transition layer alone.

Surface Roughness

One might wonder whether an alternate explanation for the apparent reduction in the amplitude of the reflectance oscillations could be roughness on the dissolving polymer surface. Using simple scattering theory it can be shown that the presence of a rough surface at the polymer/solvent interface would result in a reduction of the amplitude of the reflectance oscillations, but the average value of the reflectance would also be reduced. If surface roughness were present one would calculate an erroneous polymer refractive index when applying the equations derived for the presence of a transition layer. For the polymers used in this study the refractive index was verified to be correct by other means. Thus it appears the formation of a transition layer is the correct explanation for the observed behavior.

QUANTITATIVE ANALYSIS OF THE TRANSITION LAYER

The magnitude of the observed amplitude reduction factor may be used as a gauge of the thickness of the transition layer between the solvent and the glassy polymer. A value of $f = 1$ would correspond to a perfectly sharp interface, i.e. a transition layer of zero thickness. Values of $f < 1$ correspond to thicker transition layers. A more quantitative analysis is also possible. In principle, one can calculate an absolute thickness

of the transition layer, provided the shape of the concentration profile is known. For simplicity, this profile may be expressed in terms of refractive index (as in figure 4). It can be shown that the variation in refractive index through the transition layer is to a good approximation proportional to the variation in concentration. It is assumed that the transition layer has a finite thickness δ and that the refractive index in the layer varies only in the direction perpendicular to the surface, for which the distance variable is z . The profile may be simplified further by scaling the variables of thickness and refractive index (see figure 5).

$$u = \frac{z}{\delta} \quad (7)$$

$$g(u) = \frac{n(u) - n_i}{n_0 - n_i} \quad (8)$$

The resulting expressions that quantify the transition layer can be derived from optical theory of inhomogeneous layers. The amplitude reduction factor f is equal to the magnitude of the complex quantity $F(\gamma)$ and the phase angle θ_i is the complex phase arg of $F(\gamma)$.

$$f = |F(\gamma)| \quad (9)$$

$$\theta_i = \arg(F(\gamma)) \quad (10)$$

where

$$F(\gamma) = \int_0^{\infty} e^{i\gamma u} \frac{-dg(u)}{du} du \quad (11)$$

$$\gamma = \delta/l \quad (12)$$

$$l = \frac{\lambda}{4\pi n_e \cos \theta_e} \quad (13)$$

$$n_e = \frac{n_i + n_o}{2} \quad (14)$$

$$\cos \theta_e = \left[1 - \left(\frac{n_i \sin \theta_i}{n_e} \right)^2 \right]^{1/2} \quad (15)$$

Equation 11 for $F(\gamma)$ results when the reflection coefficient of the transition layer is calculated using the Rayleigh-Gans or Born approximation.¹²⁻¹⁴ Physically, this amounts to treating the transition layer as a continuous weakly reflecting region in which the local differential reflection coefficient is $|\nabla n|/2n$,¹⁴⁻¹⁷ where ∇n is the gradient of refractive index. Weakly reflecting means that the total change in refractive index is small compared with the average refractive index and that multiple reflections within the layer can be neglected. The overall reflection coefficient of the layer is found by integrating the differential reflection coefficient while incorporating the appropriate phase factor to account for propagation through

the layer. Scaling the parameters then gives $F(\gamma)$ in equation 11. Thus, one only needs to know something about the shape of the refractive index profile $g(u)$ in order to calculate directly its thickness δ from the measured values of f and θ_c . If knowledge about the profile is incomplete, then a fitting procedure needs to be used to match the thickness δ to the measured f and θ_c .

EXPERIMENTAL RESULTS

Measurements were made on various molecular weights of PMMA dissolving in MEK at 20°C. As in figure 3, the presence of the transition layer is evident by the reduction in the amplitude of the reflectance oscillations. Also, the endpoint of dissolution often occurs significantly ahead of the next extrapolated maximum in intensity. Because the reflectance is not observed to deviate from its sinusoidal variation until the endpoint of dissolution, it is postulated that this point represents the "leading edge" of the transition layer. Once this point reaches the substrate surface the remaining transition layer dissolves away rapidly. Table 1 lists the measured values of f and θ_c for the various molecular weights of PMMA dissolving in MEK. These values are plotted in figure 6.

Thickness Calculations

In order to calculate directly the thickness of the transition layer it is necessary to know the shape of its refractive index profile. Unfortunately, the exact shape of this profile is not known for these types of polymer-solvent systems. However, it is still instructive to calculate the thickness based on some simple model profiles. The profile shapes (figure 7) of linear, cosine, step-linear, and step-exponential were chosen to approximate a realistic profile shape and still allow an analytical solution to the integral in Equation 11. The functional form of these profiles and their derivatives as they would appear in equation 11 are listed in Table 2.

The thickness of the transition layer can be calculated to match the measured values of f and ϕ_c . The linear and cosine profiles contain only one adjustable parameter: the normalized transition layer thickness γ , so in general the observed values of f and ϕ_c cannot both be satisfied at the same time. The step-linear and step-exponential profiles contain two adjustable parameters: γ and the step fraction q . For the latter two profiles it is assumed that the observed endpoint of controlled uniform dissolution occurs when the step edge of the transition layer reaches the substrate surface. The occurrence of these step-like profiles has been observed on a much larger scale by Deberreiter² in the dissolution of polystyrene.

In principle one could perform the above analysis for any profile shape, although it might require numerical integration

and tedious iteration to solve for the transition layer thickness. In practice it is convenient to use a graphical procedure. As an example, figure 8 is a chart of transition layer thickness as a function of phase shift for the step-linear profile, with γ and q as adjustable parameters. In this case one only needs to read off the unique values of normalized thickness γ and step fraction q for measured values of f and θ_{11} .

Table 3 lists the calculated thicknesses of the transition layer of PMMA for the four model profiles. Although not entirely obvious from the values given in Table 3 the actual physical thicknesses are very close for all four model profiles. This can be seen more clearly in figure 9 where the actual profiles have been plotted on the same scale for one molecular weight of PMMA. Despite deviations at the tail ends the profiles overlap remarkably well. Thus, even though the exact profile shape is not known, it is reasonable to conclude that the transition layer thickness calculated by any of the model profiles is not far from the actual thickness. The same kind of consistency in overall thickness has been obtained elsewhere by fitting a family of one-parameter refractive index profiles to photometry data from the reflection of light from an interface separating the liquid and vapor phases of a fluid near its critical point.¹⁶

CONCLUSIONS

The technique just described is useful for approximating the thickness of the transition layer for polymers that dissolve with little or no swelling. Because the calculated thickness does not depend strongly on the assumed concentration profile shape it is reasonable that a calculated thickness will closely approximate the actual thickness. However, for the same reason experimental measurements are not likely to distinguish among various theoretical models based on profile shape alone. Application of this technique to polymer-solvent systems that exhibit both swelling and dissolution is not as straightforward since these systems are generally characterized by a non-uniform dissolution rate and damped reflectance oscillations, i.e. T and f are not constant. However, at least some qualitative information about the profile may be obtainable in such cases.

The reflectance of the dissolving film is not observed to deviate from its sinusoidal shape until the leading edge of the transition layer reaches the substrate surface. At that time the remaining transition layer dissolves away rapidly. It appears that the rate of the dissolution process is governed primarily by what is happening near the leading edge -- the interface with the solid polymer -- rather than by what is happening elsewhere in the transition layer. Although it does not provide direct detailed information about the shape of the concentration profile in the transition layer, this technique may be helpful in the

development of theoretical models for the dissolution of polymers by revealing the length scales over which the dissolution process takes place.

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TABLE 1: Amplitude reduction factor f , and phase shift angle θ_+ , due to the transition layer for various molecular weights of PMMA dissolving in MEK at 20°C.

Molecular Weight			
M_w	M_w	f	θ_+ (degrees)
27 x 10 ³	37 x 10 ³	1.0	4
29	52	1.0	4
34	61	1.0	4
35	63	0.97	9
67	134	0.93	8
97	170	0.90	12
100	150	0.89	10
160	320	0.89	25
180	270	0.88	15
220	500	0.85	24
220	500	0.87	30
360	950	0.79	30
360	950	0.80	33
1000	1400	0.71	35

TABLE 2

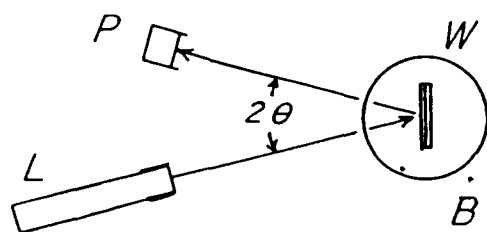
MODEL TRANSITION LAYER CONCENTRATION PROFILES

PROFILE SHAPE	$g(u)$	$dg(u)/du^*$
1. LINEAR	$1 - u$	-1
2. COSINE	$0.5(1 + \cos \pi u)$	$-0.5\pi \sin \pi u$
3. STEP-LINEAR	$q(1 - u)$	$-q - (1 - q)\delta(u)$
4. STEP-EXPONENTIAL	$qe^{-u/q}$	$-e^{-u/q} - (1 - q)\delta(u)$

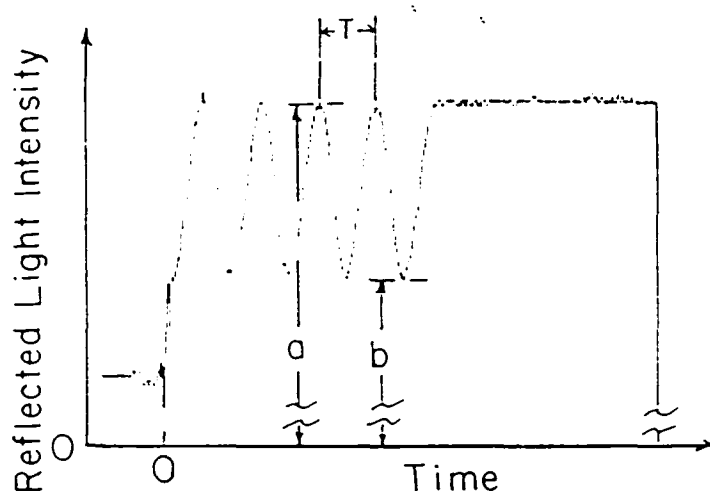
* Note that here $\delta(u)$ represents the Dirac delta function and is necessary to account for reflection at the step portion of the profile in equation 11. It should not be confused with the transition layer thickness δ elsewhere in the text.

TABLE 3: Calculated transition layer thickness δ , and step fraction q , for PMMA using various model profile shapes. Units of δ are micrometers.

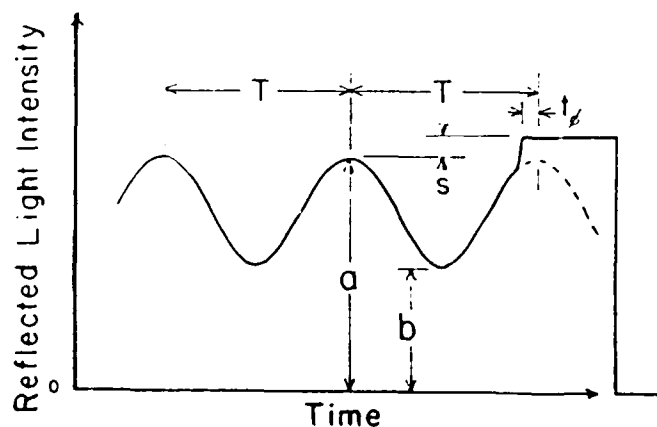
Molecular Weight		Linear	Cosine	Step-linear		Step-exp.	
M_n	M_w	δ	δ	δ	q	δ	q
27 x 10 ³	37 x 10 ³	0	0	0	0	0	0
29	52	0	0	0	0	0	0
34	61	0	0	0	0	0	0
35	63	0.031	0.041	0.027	0.40	0.013	0.40
67	134	0.047	0.063	0.053	0.19	0.022	0.28
97	170	0.057	0.075	0.063	0.27	0.023	0.41
100	150	0.060	0.079	0.074	0.22	0.027	0.32
160	320	0.060	0.079	0.053	0.63	0.019	0.80
180	270	0.062	0.083	0.065	0.34	0.024	0.50
220	500	0.070	0.093	0.063	0.52	0.023	0.76
220	500	0.065	0.086	0.057	0.68	0.021	1.0
360	950	0.084	0.11	0.076	0.56	0.030	0.21
360	950	0.081	0.11	0.071	0.62	0.028	0.70
1000	1400	0.10	0.13	0.079	0.54	0.038	0.32



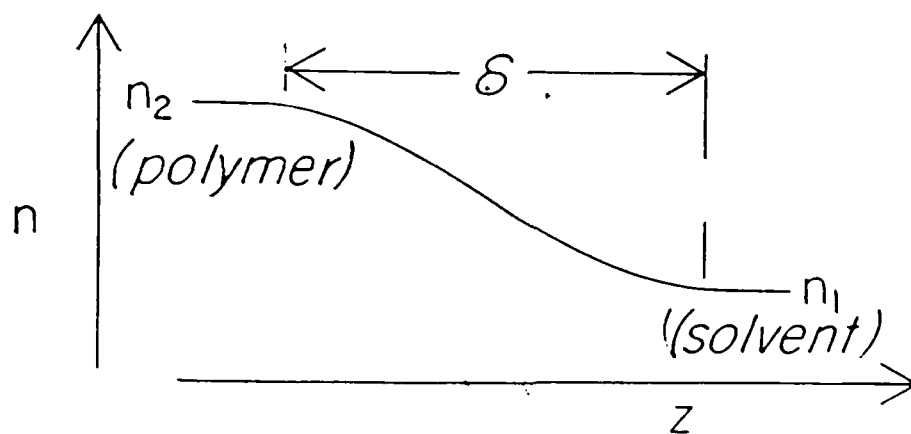
1. Interferometer for monitoring polymer dissolution. Beam from laser, L, is reflected at angle θ from coated wafer, W, immersed in solvent bath, B. Reflected light is measured with photocell, P.



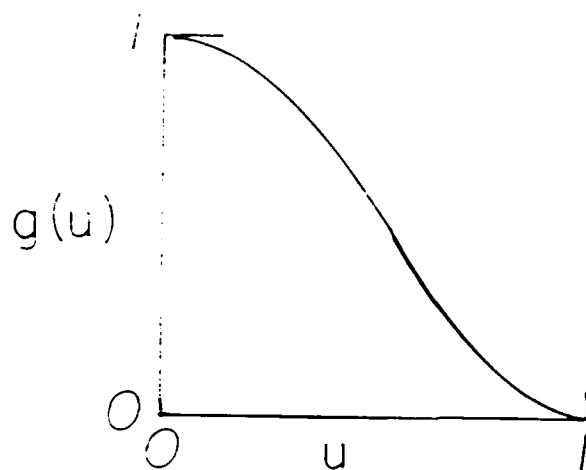
2. Typical reflected light intensity trace from polymer film with a negligible transition layer. This example used a personal computer interfaced with the photocell to reproduce the signal. The period T and amplitudes a and b are used to calculate the dissolution rate.



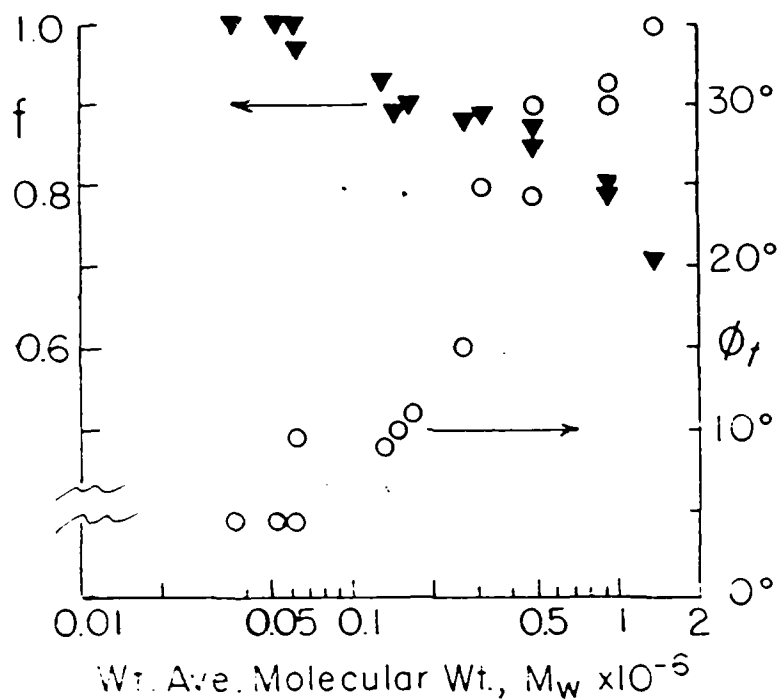
3. Trace of reflected light intensity when transition layer is present. The added features (beyond Fig. 2) are the offset, s , and the phase difference, t_p .



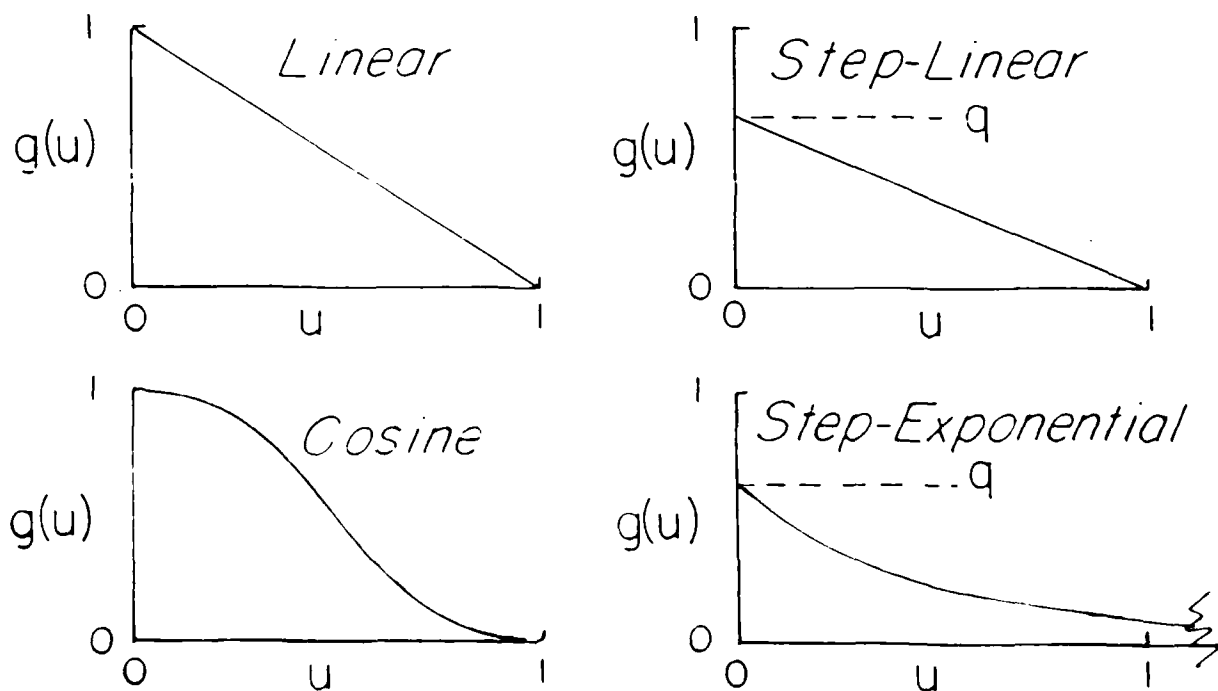
4. Refractive index n profile in the transition layer of thickness δ where z is distance



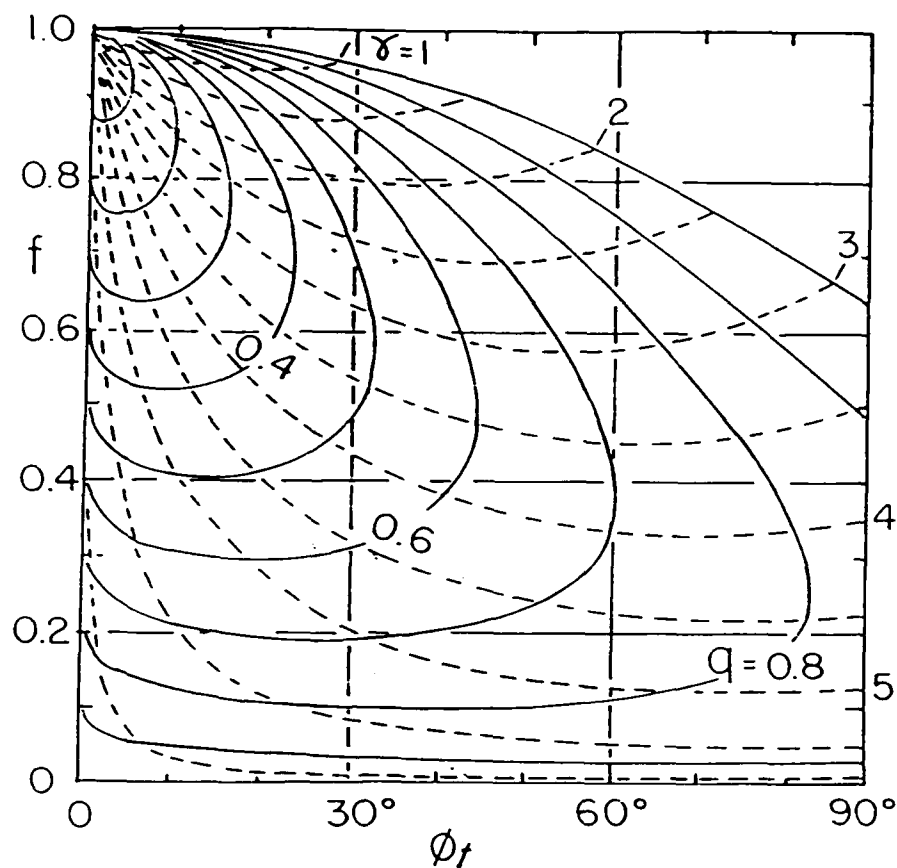
5. Scaled refractive index profile where u and $g(u)$ are given by equations 7 and 8.



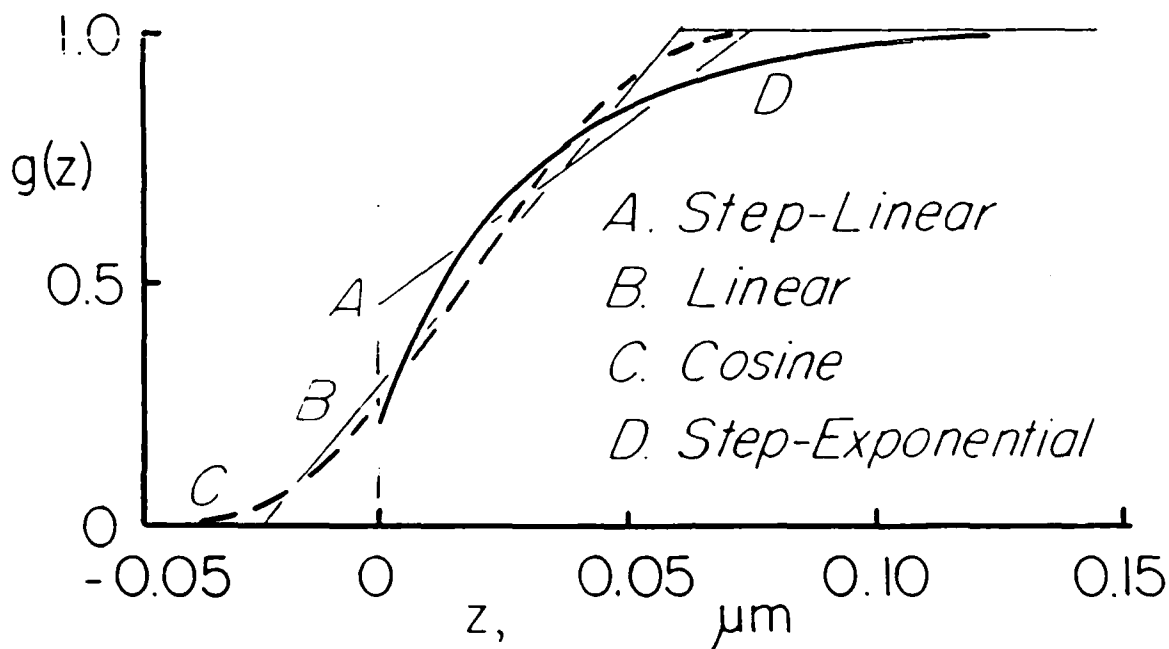
6. Experimental results for PMMA dissolving in MEK at 20°C where f is the Amplitude reduction factor and ϕ_f is the Phase shift angle (see equations 4 and 5).



7. Profiles for the four models of Table 2.



8 Chart of reduced transition layer thickness, δ , as a function of the measured Amplitude reduction factor, f , and the Phase shift angle, ϕ_t . The parameter q takes into account the step change in concentration at the polymer-transition interface.



9. The experimentally fitted model profiles are seen to be almost indistinguishable from each other for all four models. The data used here are for PMMA of $M_w = 950,000$ in MEK at 20°C.

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